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In re Patent Application of)
Kenji KASAHARA et al.)
Serial No. 09/640,521)
Filed: August 17, 2000)
For: LASER APPARATUS AND)
LASER ANNEALING METHOD)

Art Unit: 1725
Examiner: G. Evans

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with The United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on January 17, 2003.

Adele M. Stamper
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SUPPLEMENTAL AMENDMENT

Honorable Commissioner of Patents
Washington, D.C. 20231

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Technology Center 2600

Sir:

Further to the Amendment filed on December 2, 2002, please further amend the above-identified application as follows:

IN THE CLAIMS:

Please amend claim 30 as follows:

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TC 1700

30. (Twice Amended) A laser apparatus, comprising:
- a laser source for emitting a laser light;
 - a half mirror for dividing the laser light into a first laser light and a second laser light;
 - an optical system for guiding the first laser light and the second laser light onto a top surface and a back surface of an object to be treated, respectively,
 - wherein the optical system includes a filter for attenuating the second laser light;
 - a substrate holder for holding a substrate,
 - wherein a semiconductor film is formed over the substrate.